

Photoinjector General

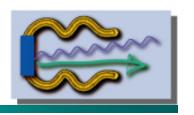
+

Photocathodes

presented by Konrad Elsener (CERN-AB)



Acknowledgements (PHIN)



We acknowledge the support of the European Community-Research Infrastructure Activity under the FP6 "Structuring the European Research Area" programme (CARE, contract number RII3-CT-2003-506395).

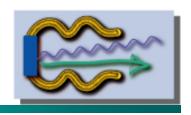








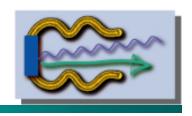
Outline

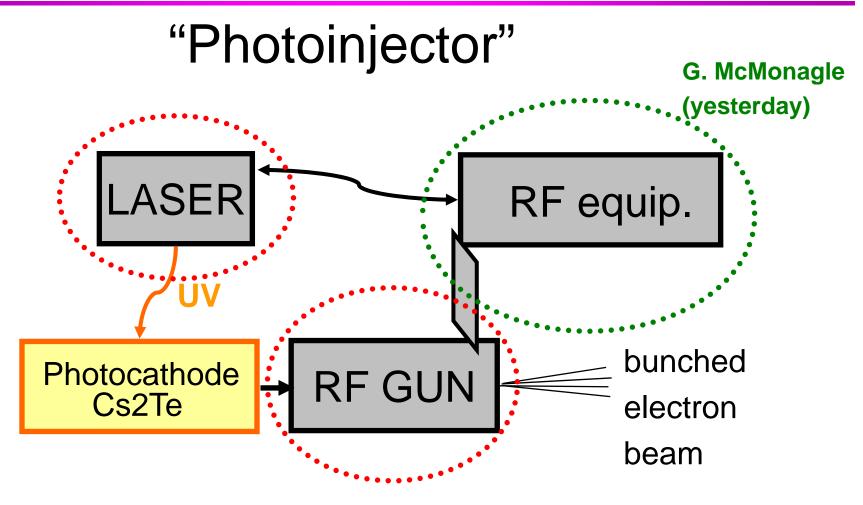


- Overview
- Photocathodes: Status + Outlook (photocathode for CLEX)
- PHIN in CTF2
- Summary



Overview

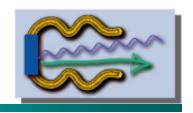




...cf. next two talks...



Photocathodes



many thanks to Eric Chevallay

- cf. presentation by R. Losito, 17 Jan. 2007
- HIGHLIGHT end of 2006:

Photocathode No. 166 produced (after > 3 years interruption)

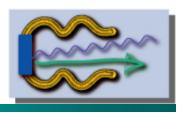
Cs-Te cathode, co-evaporation,

Quantum Efficiency > 6%

very detailed description of No. 166: CTF3-Note-089



Photocathodes – No. 167



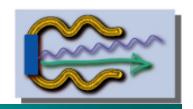
HIGHLIGHT 2007:

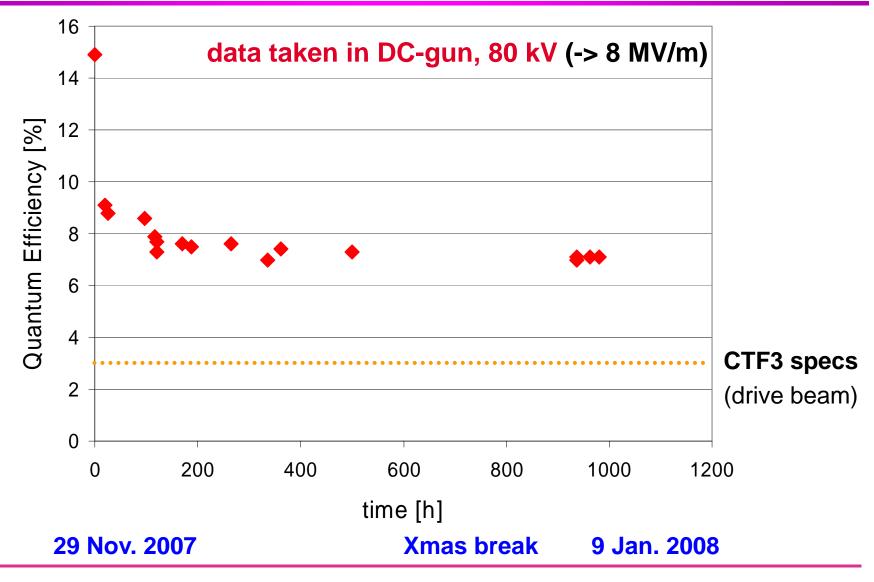
Photocathode No. 167 produced 29 November (Cs-Te cathode, co-evaporation)

Quantum Efficiency Lifetime measured during 1000 hours



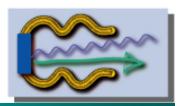


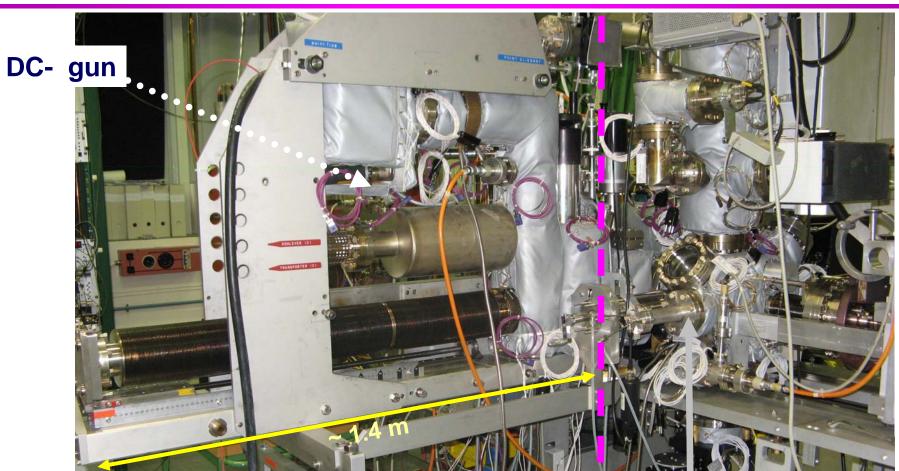






Photocathodes – No. 167





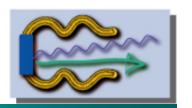
transport carrier

preparation chamber

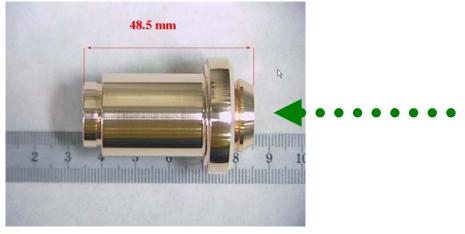
manipulator



Photocathodes - No. 167



basic unit: Cu "plug"

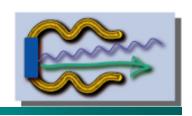


on the "arm" inside the transport carrier: up to **4 plugs**





Photocathodes



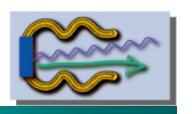
Process Control and Reproducibility

(A. Barbiero and E. Chevallay)

- cleanliness / UHV vacuum

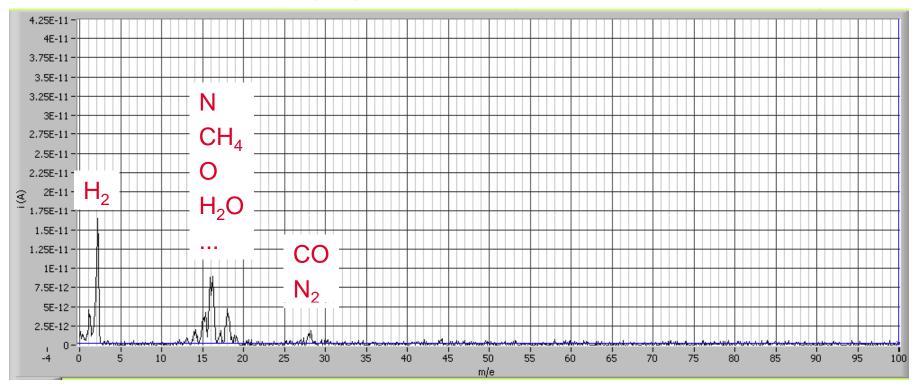


Photocathodes - vacuum



a long period of improvements, pumping, leak testing, baking-out, leak testing, repair, pumping, baking out, ...

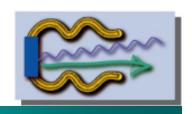
vacuum before cathode preparation: < 3x10⁻¹¹ mbar



residual gas analysis in preparation chamber (29 Nov. 2007)



Photocathodes – film thickness



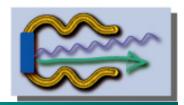
Process Control and Reproducibility

(A. Barbiero and E. Chevallay)

- cleanliness / UHV vacuum
- film thickness monitoring (Te, not Cs)
 - -> new stylus profilometer, calibrated



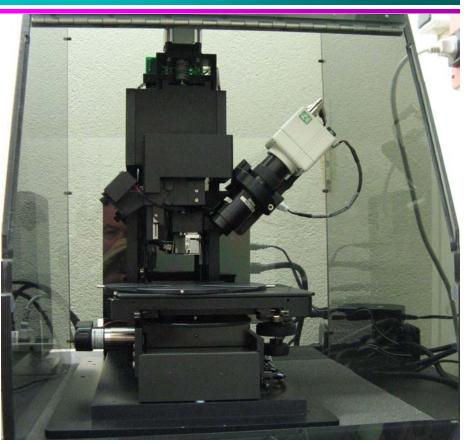
Photocathodes - film thickness





Te films on quartz substrate

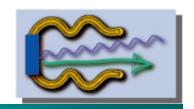


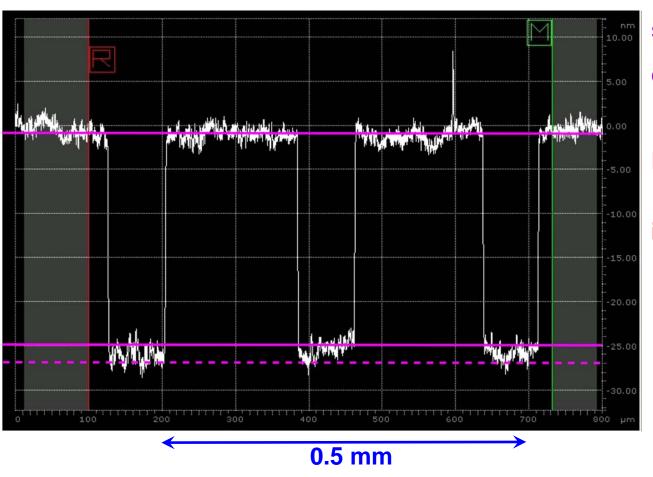


new Stylus Profilometer



Photocathodes – film thickness





solid lines: Δ =24 nm

dashed line: Δ =26 nm

Result:

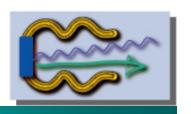
Profilometer intrinsic error < 2 nm

cross-check of Stylus Profiler using a calibrated sample* (Rank Taylor Hobson) with 3 grooves, 24 nm each

^{*} sample on loan from CERN-TS/MME (W. Vollenberg)



Photocathodes – transfer arm



Process Control and Reproducibility

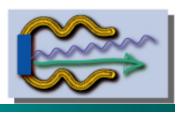
(A. Barbiero and E. Chevallay)

- cleanliness / UHV vacuum
- film thickness monitoring
 - -> stylus profilometer, calibrated
- possibility of cathode chemical analysis (X-ray Photoel. Spectr.)
 - -> new, smaller transfer arm (for 1 plug)

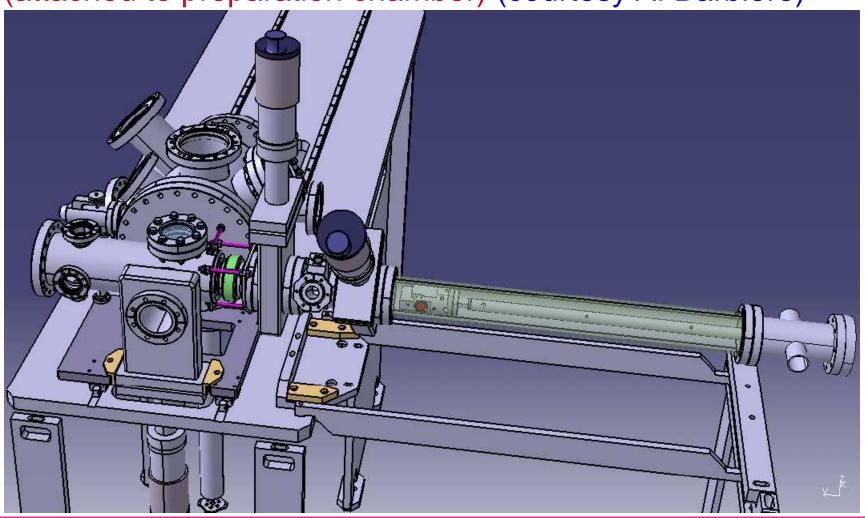
(collaboration with team of M. Taborelli / TS-MME)



Photocathodes – transfer arm

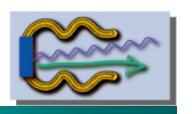


(attached to preparation chamber) (courtesy A. Barbiero)





Photocathodes – plug surfaces



Process Control and Reproducibility

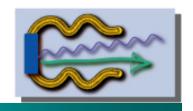
(A. Barbiero and E. Chevallay)

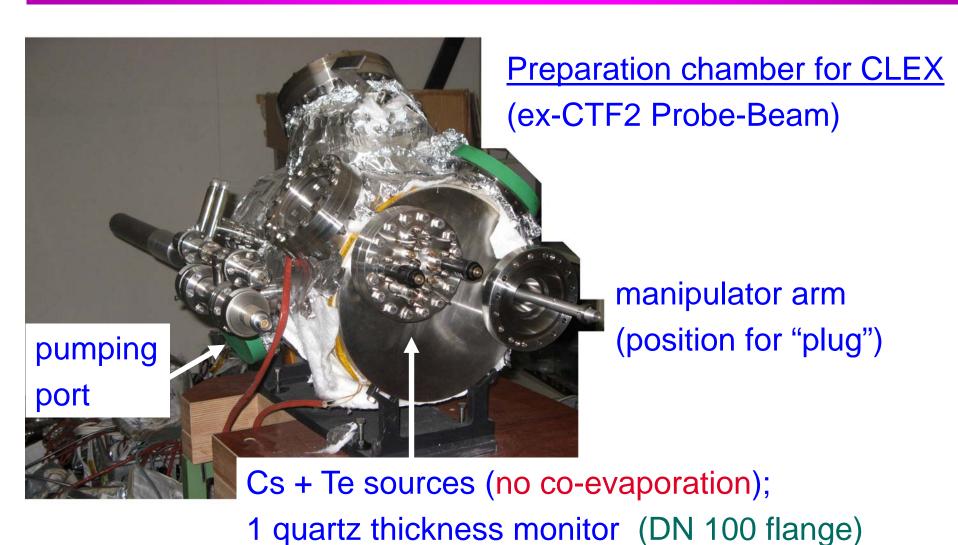
- cleanliness / UHV vacuum
- film thickness monitoring
 - -> stylus profilometer, calibrated
- possibility of cathode chemical analysis (XPS)
 - -> new transfer arm
- reproducible "plug" surface
 - -> test programme on surface preparation + analysis

(work in progress - No. 166 and No. 167 are very different)



photocathode for CLEX

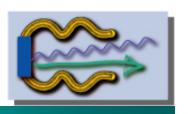


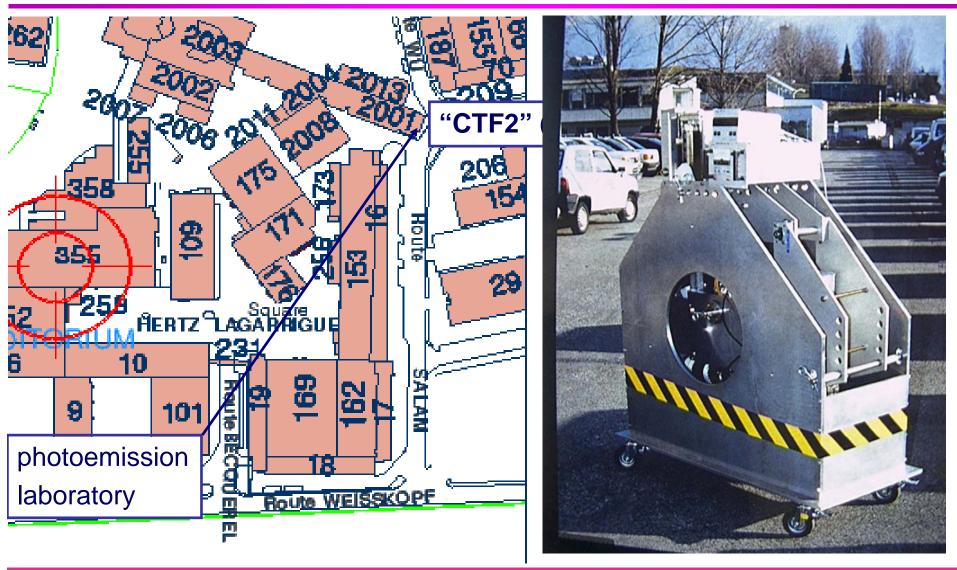


EDMS No. 888499



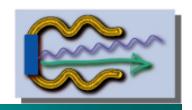
"CTF2"







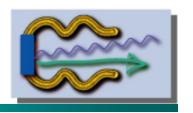
"CTF2" - status







Acknowledgments



Nathalie Lebas: expert help with the laser

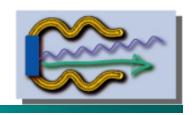
Arnaud Brielmann: expert help with controls

and interlocks

(for equipment safety)



Summary + Outlook

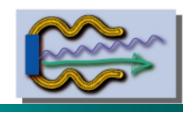


- Photoemission Laboratory: ready for production of cathodes
- Cs-Te cathode No. 167: ready for PHIN
- work in progress to improve reproducibility
- near future: CLEX cathode

continue contributions to PHIN in "CTF2"

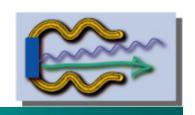


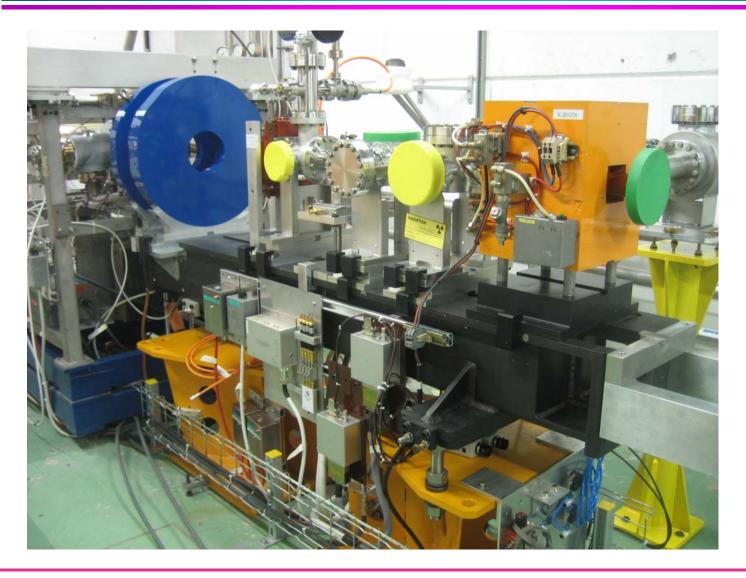
spare slides





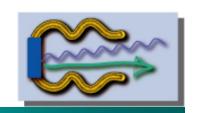
spare slides

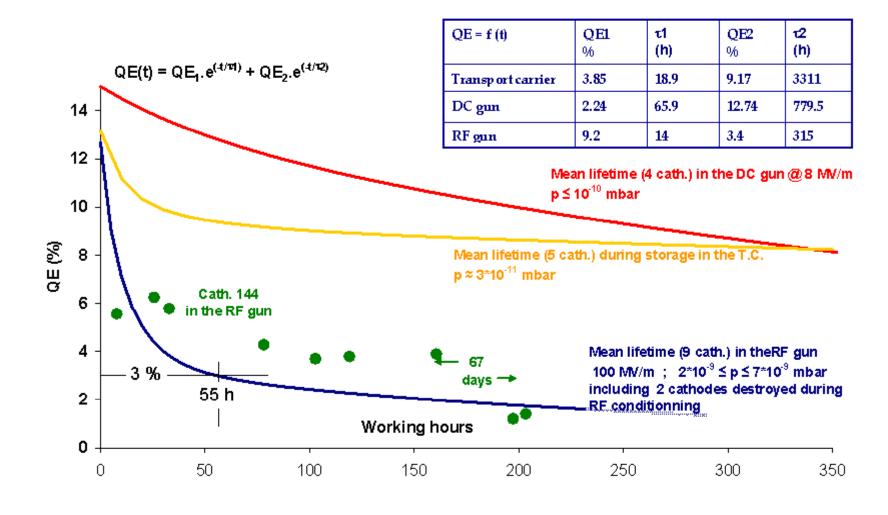




8 Nov. 2007









PHIN overview

